

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: Unknown
Inventor: Sway-Chuang
Serial No. To Be Assigned
Filed: Herewith
For: Microfluidic Component Providing Multi-Directional
 Fluid Movement
Attorney Docket No.: 64,600-116

DISCLOSURE STATEMENT
UNDER 37 C.F.R. § 1.56

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with 37 C.F.R. § 1.56, the art listed and identified on the attached Form PTO-1449 is being submitted herewith for consideration by the Examiner.

It is Applicant's opinion that the claims presently on file patentably distinguish the present invention from each of these references. The above references are being cited only in the interests of candor and without any admission that they constitute

U.S.S.N.: To Be Assigned

statutory prior art or contain matter which anticipates the invention or which would render the same obvious, either singly or in combination, to a person of ordinary skill in the art.

Respectfully submitted,

TUNG & ASSOCIATES

By 

Randy W. Tung

Reg. No. 31,311

838 W. Long Lake Road

Suite 120

Bloomfield Hills, MI 48302

FORM PTO-1449 (MODIFIED) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	ATTY DOCKET NO.	SERIAL NO.
	64,600-116	To Be Assigned
	APPLICANT Sway Chuang	
	FILING DATE Filed Herewith	GROUP Unknown

REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUB CLASS	FILING DATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NO.	DATE	COUNTRY	CLAS S	SUB CLASS	TRANSLATION YES/NO
	AI						
	AJ						

OTHER ART (including Author, Title, Date, pertinent pages, etc.)

	AK	Bernard et al, "Thin Film Shape-Memory Alloy Actuated Micropumps", J. Microelectromechanical Systems, Vo. 7(2), June 1998, pp. 245-51
	AL	Jeong et al, "Fabrication and Test of a Thermopneumatic Micropump with a Corrugated p+ Diaphragm", Sensors and Actuators 83 (2000), pp. 240-55
	AM	Gong et al, "Design, Optimization and Simulation on Microelectromagnetic Pump", Sensors and Actuators, 83 (2000), pp. 200-07
	AN	Yang et al, "Design Fabrication and Testing of Micromachined Silicon Rubber Membrane Valves", J. Microelectromechanical Systems, Vol. 8(4), December 1999, pp. 393,402

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.